



00862.022170

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
	:	Examiner: D. A. Vanore
Haruhito ONO et al.)	
	:	Group Art Unit: 2881
Application No.: 09/819,907)	
	:	Confirmation No.: 5369
Filed: March 29, 2001)	
	:	
For: ELECTRON OPTICAL SYSTEM,)	December 16, 2003
CHARGED-PARTICLE BEAM EXPOSURE	:	
APPARATUS USING THE SAME, AND)	
DEVICE MANUFACTURING METHOD	:	

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated September 16, 2003, please amend the above-identified application as follows:

12/18/2003 MAHME1 00000119 09819907

02 FC:1201

172.00 0P